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				Application Number	10/551,714					
INI	FORM	ATION DISCLO	DSURE	Filing Date	July 20, 2006					
ST	ATEM	IENT BY APPLI	ICANT	First Named Inventor	EIN-ELI Yair et al					
517				Group Art Unit	1793					
	(use as	many sheets as necesse	ary)	Examiner Name	PARVINI Pegah					
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	1 Of 1 Attorney Docket Number 30579 OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS									
Examiner	Cite	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the								
Initials	No. <sup>1</sup>	item (book, magazine, journal, serial symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.								
	1	Response Dated 04 F	r 2009 From							
		the US Patent and Trademark Office Re.: Application No. 10/551,714.								
	2		Abelev et al. "Enhanced Copper Surface Protection in Aqueous Solutions							
		Containing Short-Chain Alkanoic Acid Potassium Salts", Langmuir, 23: 11281-11288, 2007.								
	3	Abelev et al. "Potassium Sobate Solutions as Copper Chemical Mechanical								
		Planarization (CMP) Based Slurries", Electrochimica Acta, 52: 5150-5158, 2007.								
	4	Abelev et al. "Potassium Sorbate - A New Aqueous Copper Corrosion Inhibitor.								
		Electrochemical and Spectroscopic Studies", Electrochimica Acta, 52: 1975-1982,								
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	5	Abelev et al. "Reprint of 'Potassium Sorbate Solutions as Copper Chemical								
		Mechanical Planarization (CMP) Based Slurries'", Electrochimica Acta, 53: 1021-								
		1029, 2007.								
	6	Ein-Eli et al. "Food Preservatives Serving as Nonselective Metal and Alloy Corrosion Inhibitors", Electrochemical and Solid-State Letters, 9(1): B5-B7, 2006.								
	7	Ein-Eli et al. "Review on Copper Chemical-Mechanical Polishing (CMP) and Post-								
	<b>'</b> i	CMP Cleaning in Ultra Large System Integrated (ULSI) - An Electrochemical								
		Perspective", Electrochimica Acta, 52: 1825-1838, 2007.								
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